

In the Specification:

Please replace paragraph 0023 on pages 7-8 with the following rewritten paragraph:

**Paragraph [0023]:**

5           Probe assembly 100 of Figure 1 also includes mask 130 which  
includes apertures 135 therein. Apertures 135 are of a size  
which is comparable to that of the outer diameter of probe wire  
200 so that aperture 135 provides a guide for motion of probe  
wires 200 as probe wire tips 201 (see Figures 2 and 3) are urged  
10 against the wafer pads. Mask 130 is substantially flat, as is  
base 110. Mask 130 is disposed at a substantially fixed distance  
from base 110 by means of sidewall support or supports 120.  
Support 120 comprises any convenient feature, mechanism or means  
for supporting mask 130 at a substantially fixed distance from  
15 base 110. Sidewall support 120 preferably comprises material  
selected from the following group: ceramic, plastic, composite or  
metal. The most important quality for selecting a material for  
sidewall support 120 is its dimensional stability over time and  
use. In preferred embodiments of the present invention sidewall  
20 120 comprises a foam material. While sidewall support 120 may  
comprise physically distinct and separate parts, it is preferred  
that it be formed as an integral unit. Such a structure is meant  
to provide dimensional stability and constancy in terms of the  
overall height of probe assembly 100. Uniformity in height helps  
25 to assure corresponding uniformity in applied contact force. In  
this regard, it is recalled from above that controlled contact  
force is a desirable aspect of the present invention: too much  
force damages the wafer pads and too little force fails to  
produce a desirably low and consistent contact resistance.